



PATENT
8565D-7213 (81839.0077)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Teruaki FUKAMI

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE WATER AND
SILICON WAFER STORAGE METHOD

Art Unit: 1744

Examiner: Soubra, I.

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6/8/01

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Commissioner for Patents
Washington D.C. 20231, on

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John P. Schenacher, Reg. No. 23,009

Name

Signature

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Date

RESPONSE TO OFFICE ACTION

Box Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated March 1, 2001, please enter and consider the following remarks.

REMARKS

Claims 1-20 are pending in the application. Reconsideration and allowance in view of the following remarks are respectfully requested.

In paragraph 1 of the Office Action, claims 1-5, 12, 14-18 and 20 are rejected under 35 U.S.C. § 103(a) as being unpatentable over Hayashida et al. in view of Suzuki et al. Hayashida et al. is said to disclose the subject matter of the claims except for the method of storing and water storage for silicon wafers. Suzuki et al. is said to intrinsically disclose a similar method in using purified water for storage of semiconductors. According to the Office Action, it would have been obvious to one of ordinary skill in the art at the time of the invention to incorporate the same

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